

RF fields simulations

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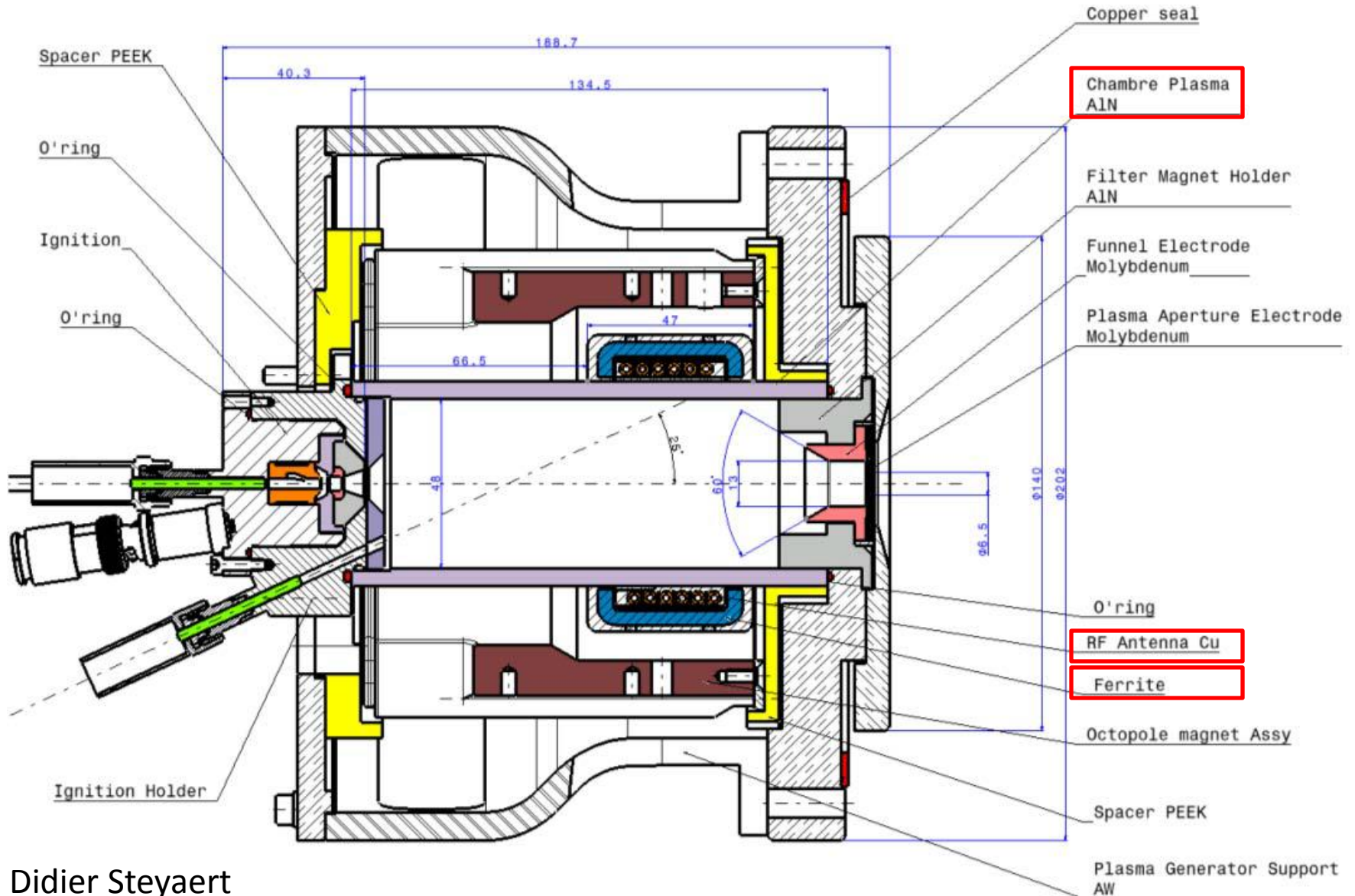
14/11/2013

Linac4 Ion Source Review, CERN

Outline

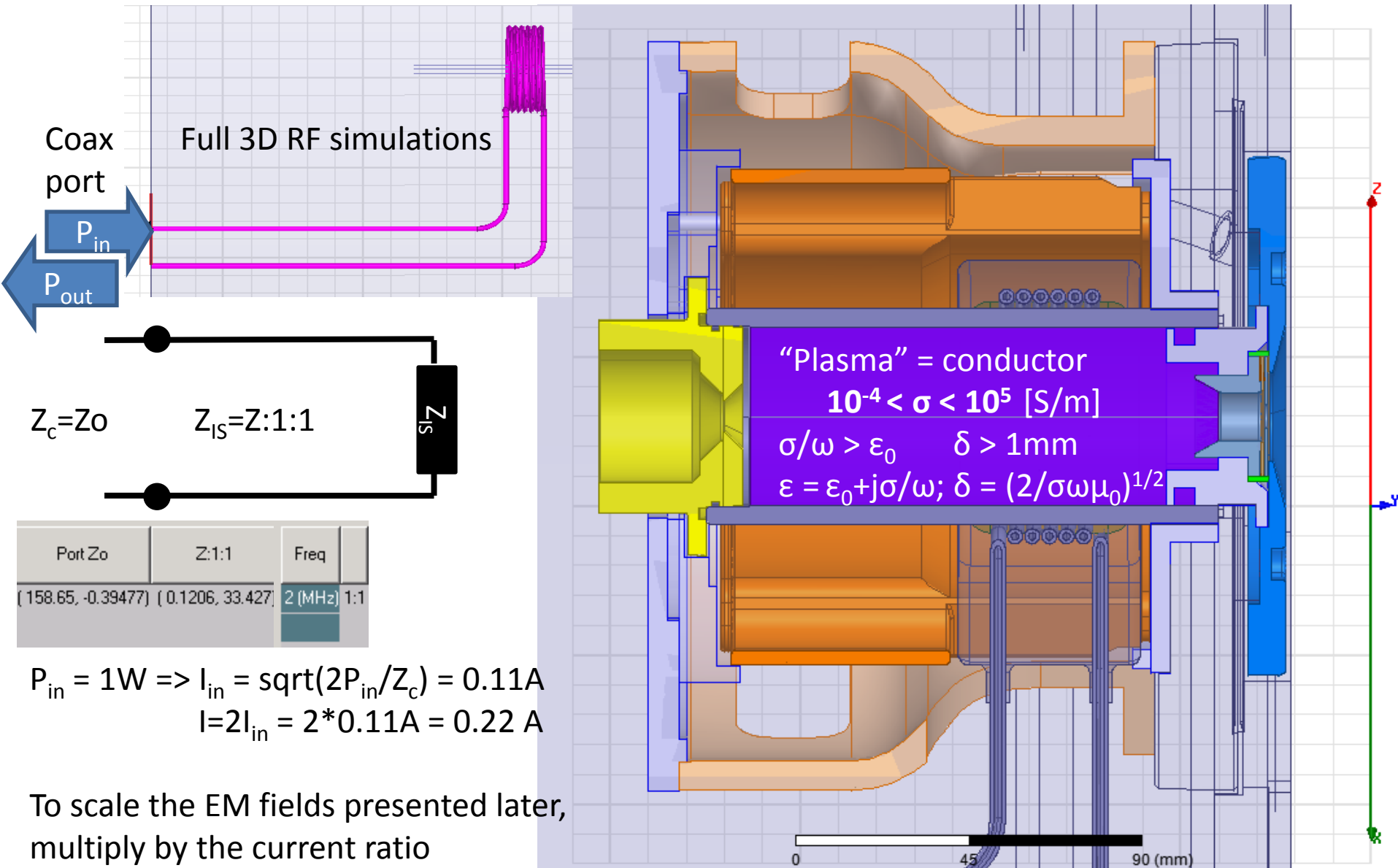
- RF field simulations setup
- Plasma model as a conductor
- Surface electric field enhancement
- EM field distribution in plasma chamber
- Ion source Impedance
- Comparison with measurements
- Variation of the ion source geometry
- Conclusions

CAD 3D model of IS-01

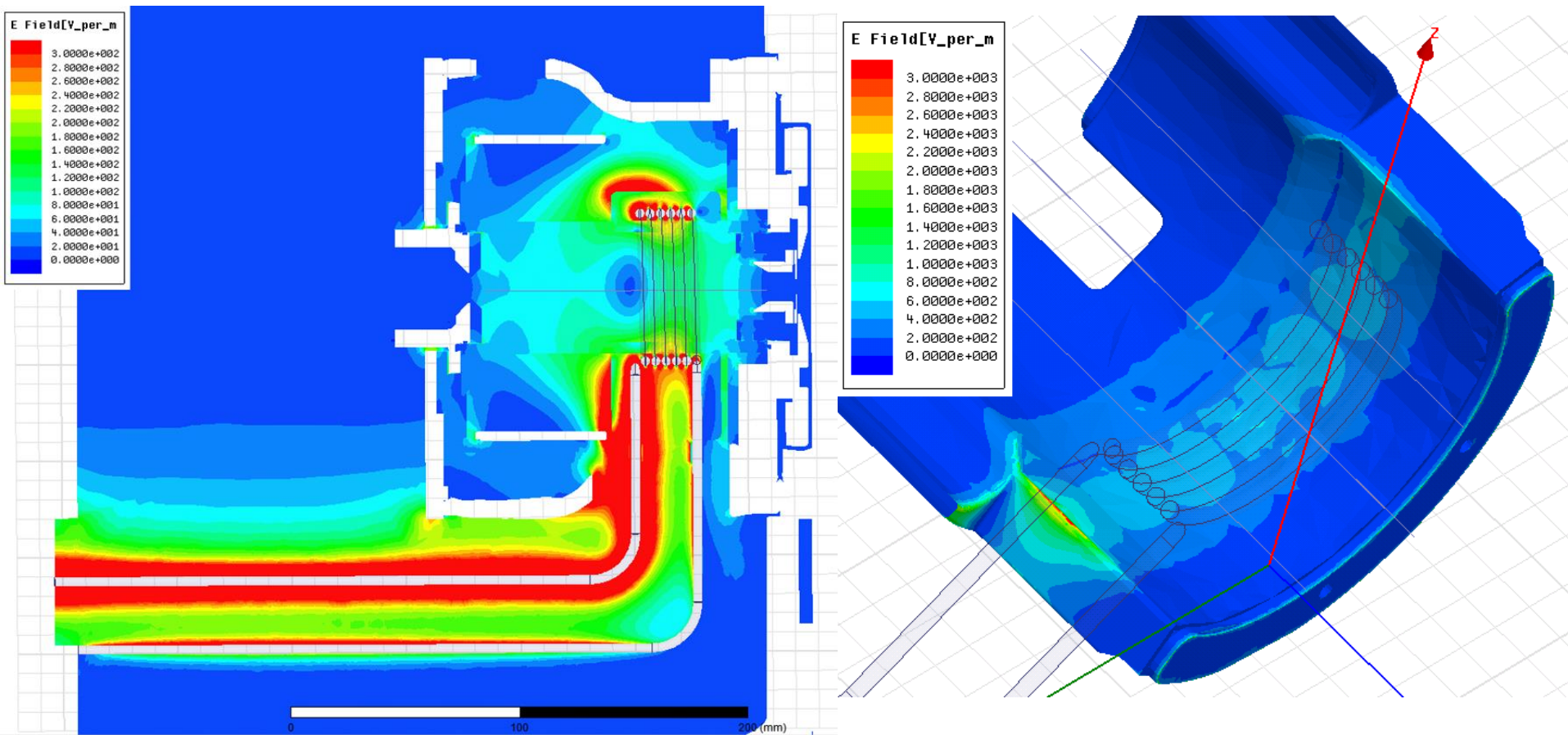


Didier Steyaert

RF simulation setup (HFSS)



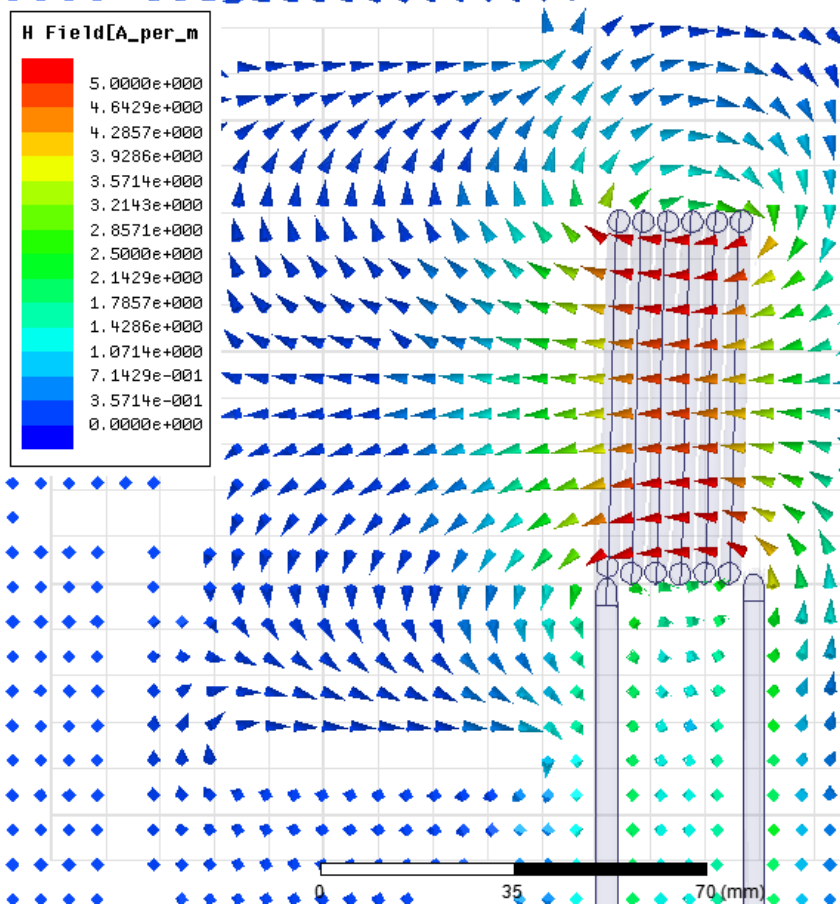
Surface electric field enhancement



Max E-field on the surface of the Cu octupole envelop for 220 A coil current is about 3 MV/m, same as air discharge threshold. This due to sharp edge close to the coil.

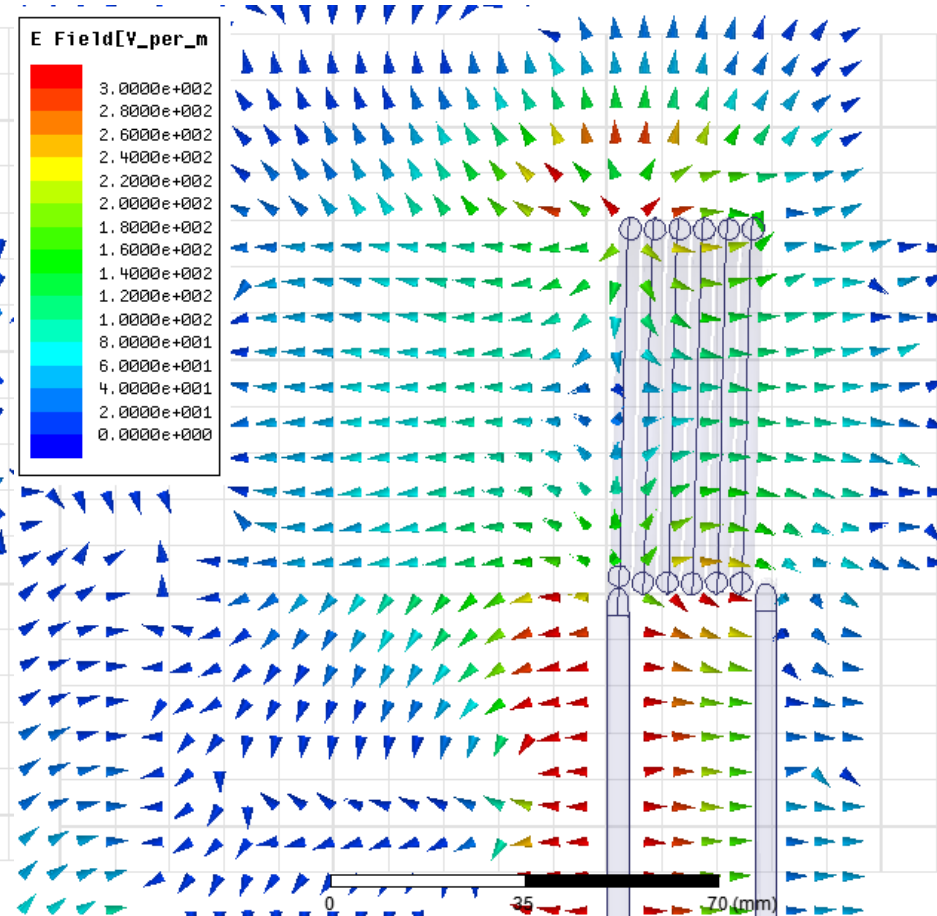
EM field distribution in plasma chamber region, $\sigma=0$

Magnetic field



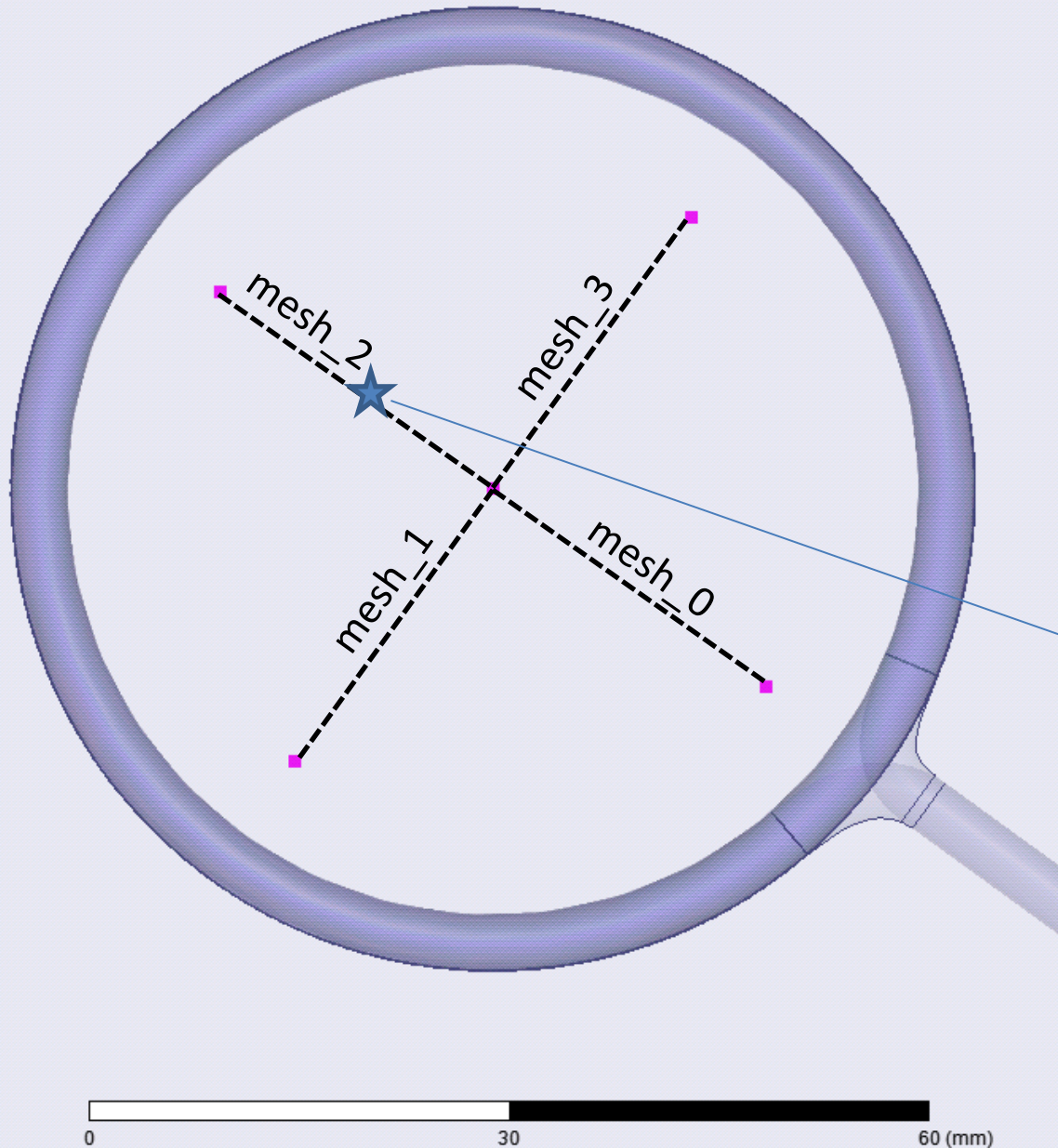
H-field is similar to the one of a solenoid

Electric field



E-field is dominated by R,Z components.
It is mainly capacitive

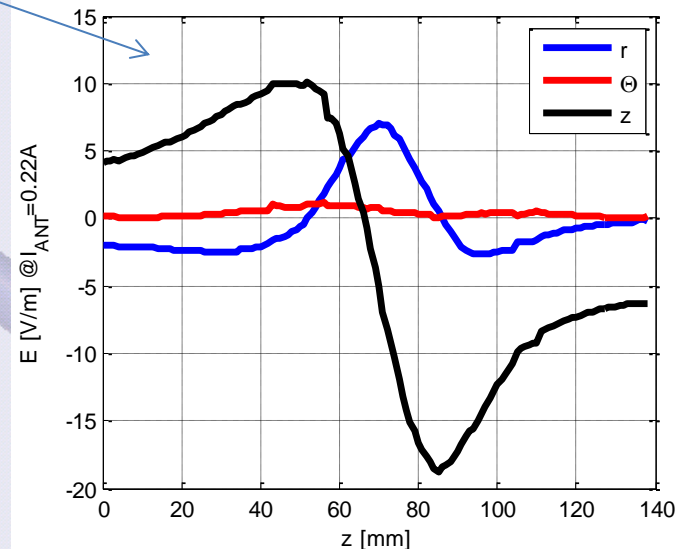
Field map for plasma simulations



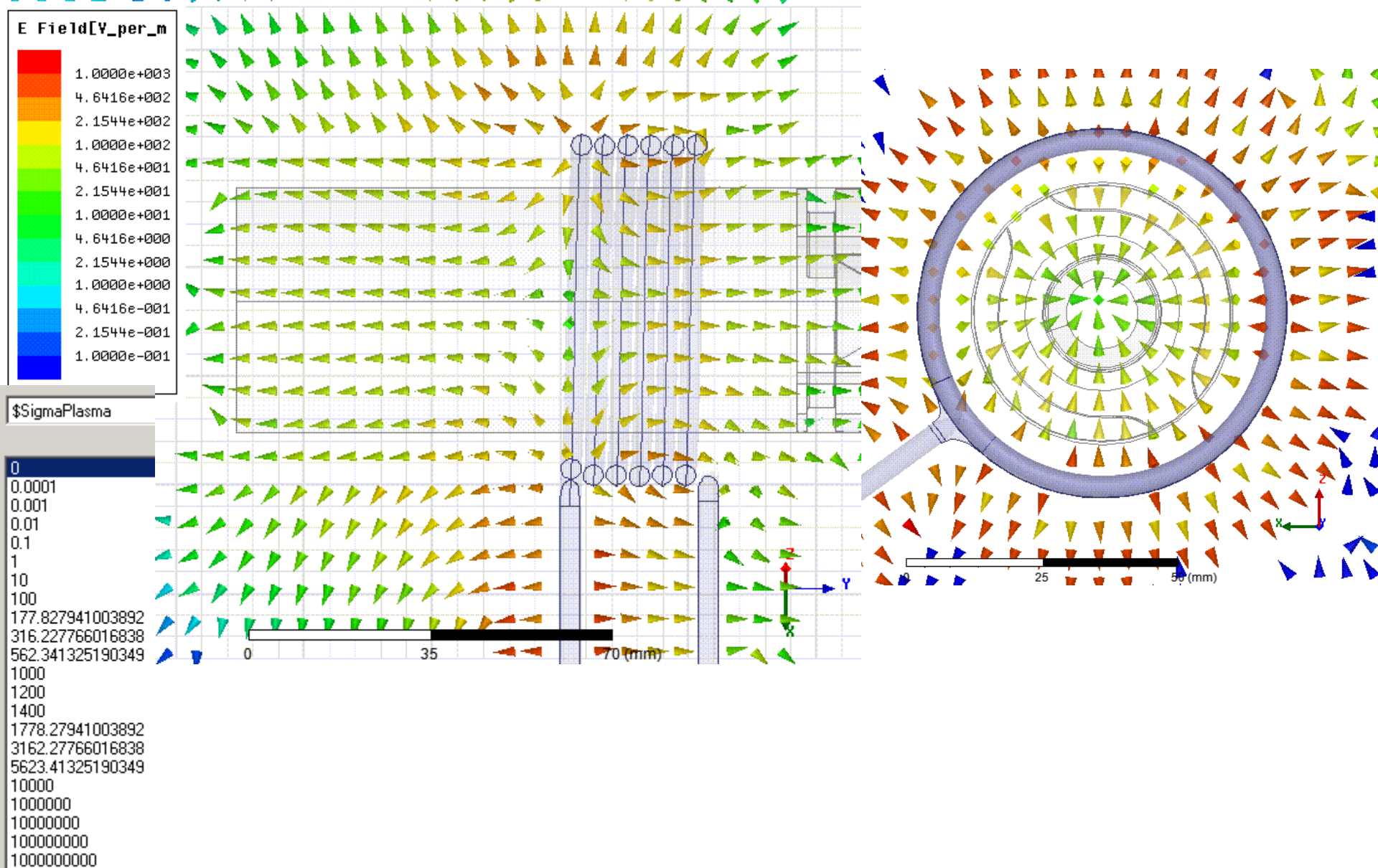
Averaging the field over 4 meshes remove radial and azimuthal components on axis $r=0$ and make the distribution quasi 2D.

To be used in the plasma simulation code with 2D field representation.

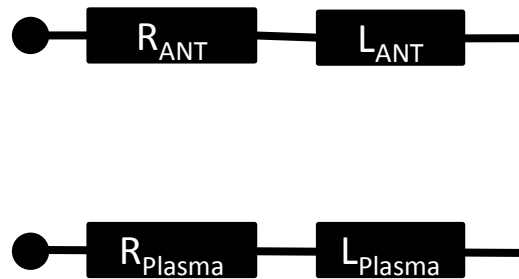
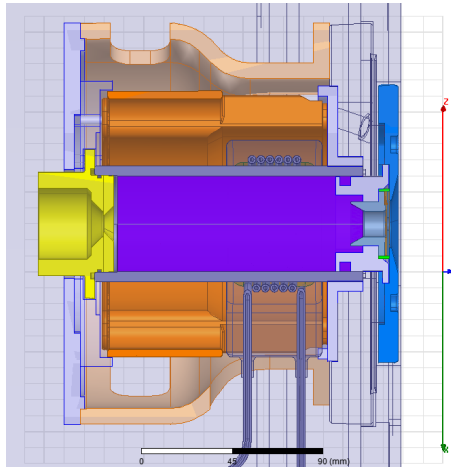
$$\text{Field} = 1/4 * [\text{field}(\text{mesh}_0) + \text{field}(\text{mesh}_1) + \text{field}(\text{mesh}_2) + \text{field}(\text{mesh}_3)]$$



E-field distribution in plasma chamber. $\sigma > 0$



Ion source impedance



Model used in the RF measurements

$$Z_{\text{Plasma}} = Z_{\text{Ant+Plasma}}(\sigma > 0) - Z_{\text{Ant}}(\sigma = 0)$$

$$Z_{\text{Ant}} = R_{\text{Ant}} + j\omega_0 L_{\text{Ant}}$$

$$Z_{\text{Plasma}} = R_{\text{Plasma}} + j\omega_0 L_{\text{Plasma}}$$

RF Measurements IS-01:

$$R_{\text{Ant}} = 0.4 \Omega$$

$$L_{\text{Ant}} = 3.2 \mu\text{H}$$

$$R_{\text{plasma}} = 4.3 \Omega$$

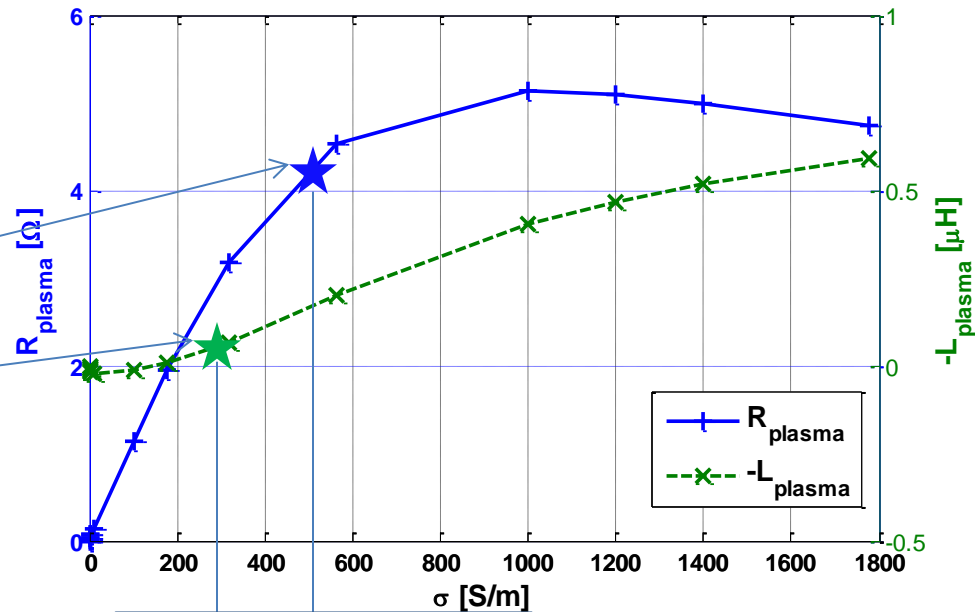
$$L_{\text{plasma}} = -0.05 \mu\text{H}$$

M. Paoluzzi

Simulations IS-01:

$$R_{\text{Ant}} = 0.263 \Omega$$

$$L_{\text{Ant}} = 3.02 \mu\text{H}$$

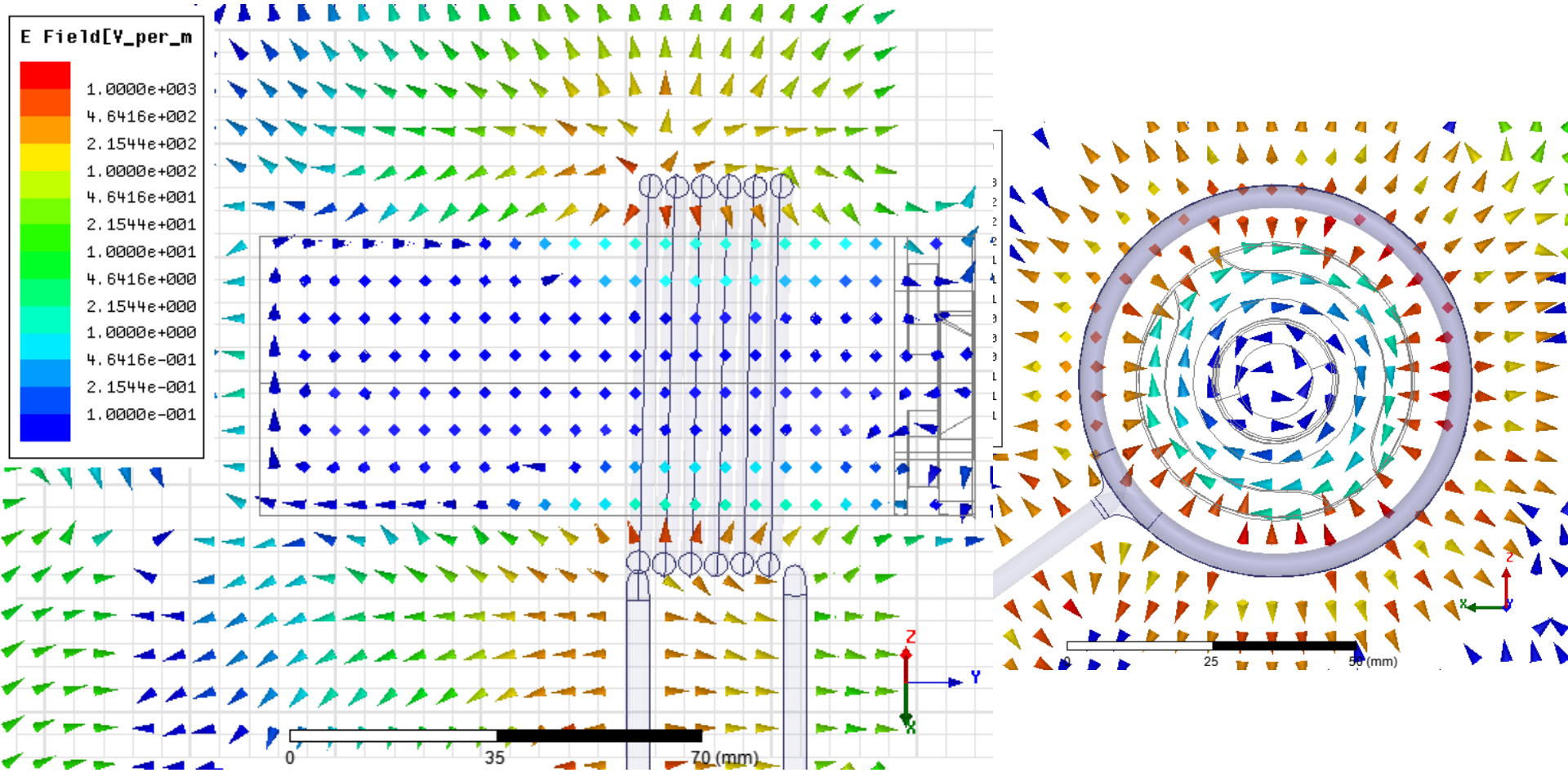


$\sigma = 300 - 500$ [S/m]

$$\sigma = \frac{n_e e^2}{m(\gamma_0 + j\omega)} \approx \frac{n_e e^2}{m(1.9 \times 10^9 P + 1.5 \times 10^{-11} n_e T_e^{-3/2})}$$

Plasma measurements (**SPL-IS**): H₂ pressure ~ 20 mTorr, n_e ~ 10¹⁸ - 10¹⁹ m⁻³ and T_e ~ 10 eV. => It gives an estimate of the conductivity of **730 - 6600 S/m** for the above given density range
R. Scrivens

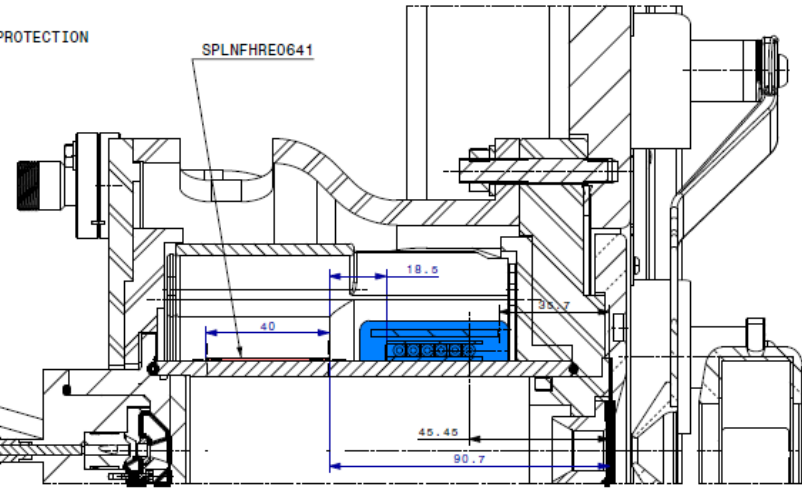
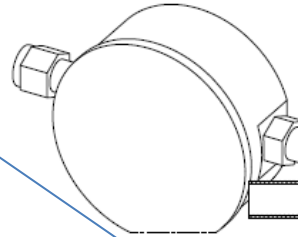
E-field distribution in plasma chamber, $\sigma = 1000 \text{ S/m}$



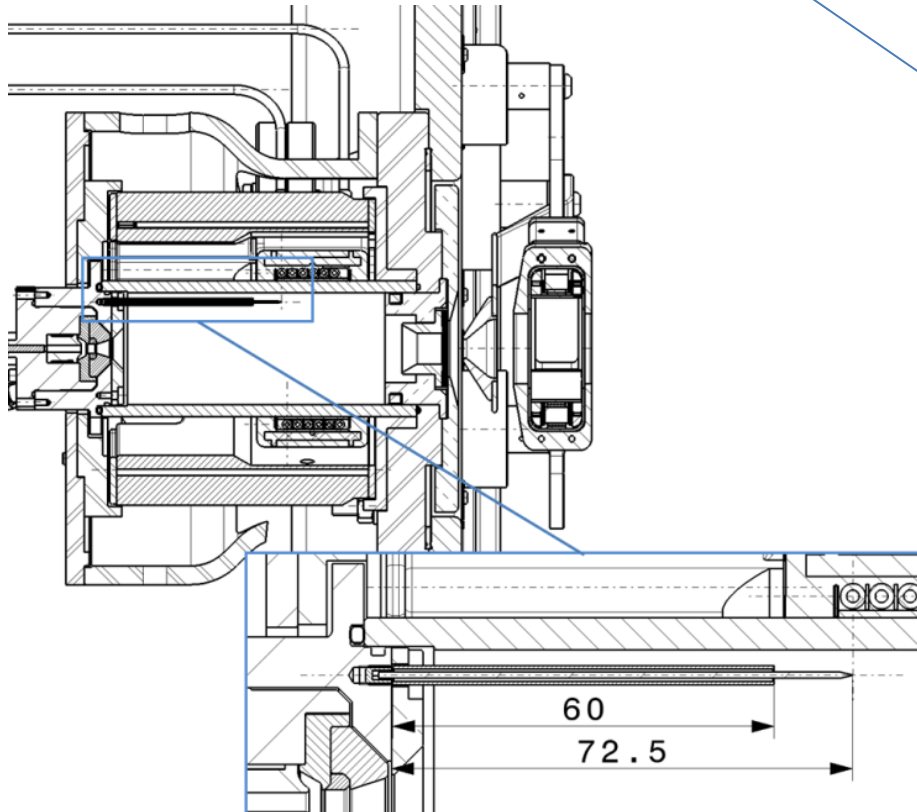
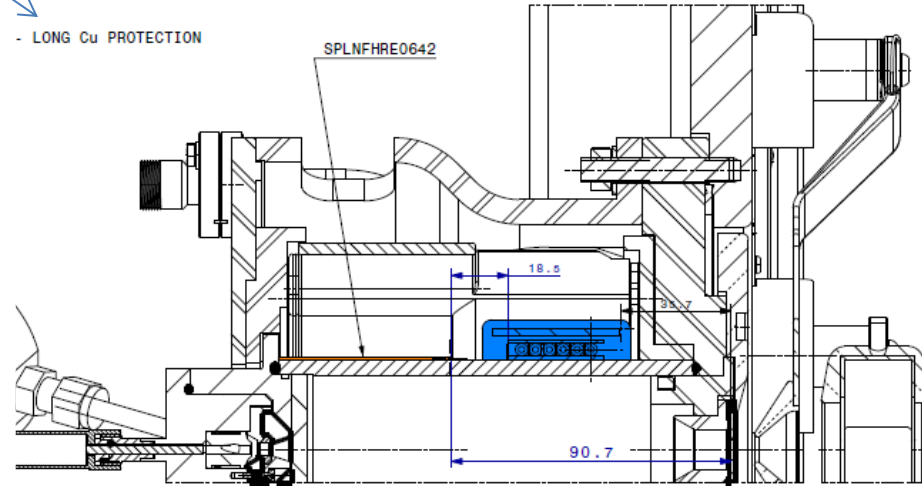
Variations: SET 1

- 1. No Cu octupole holder
- 2. Long Cu protection
- 3. Short Cu protection
- 4. W-electrode

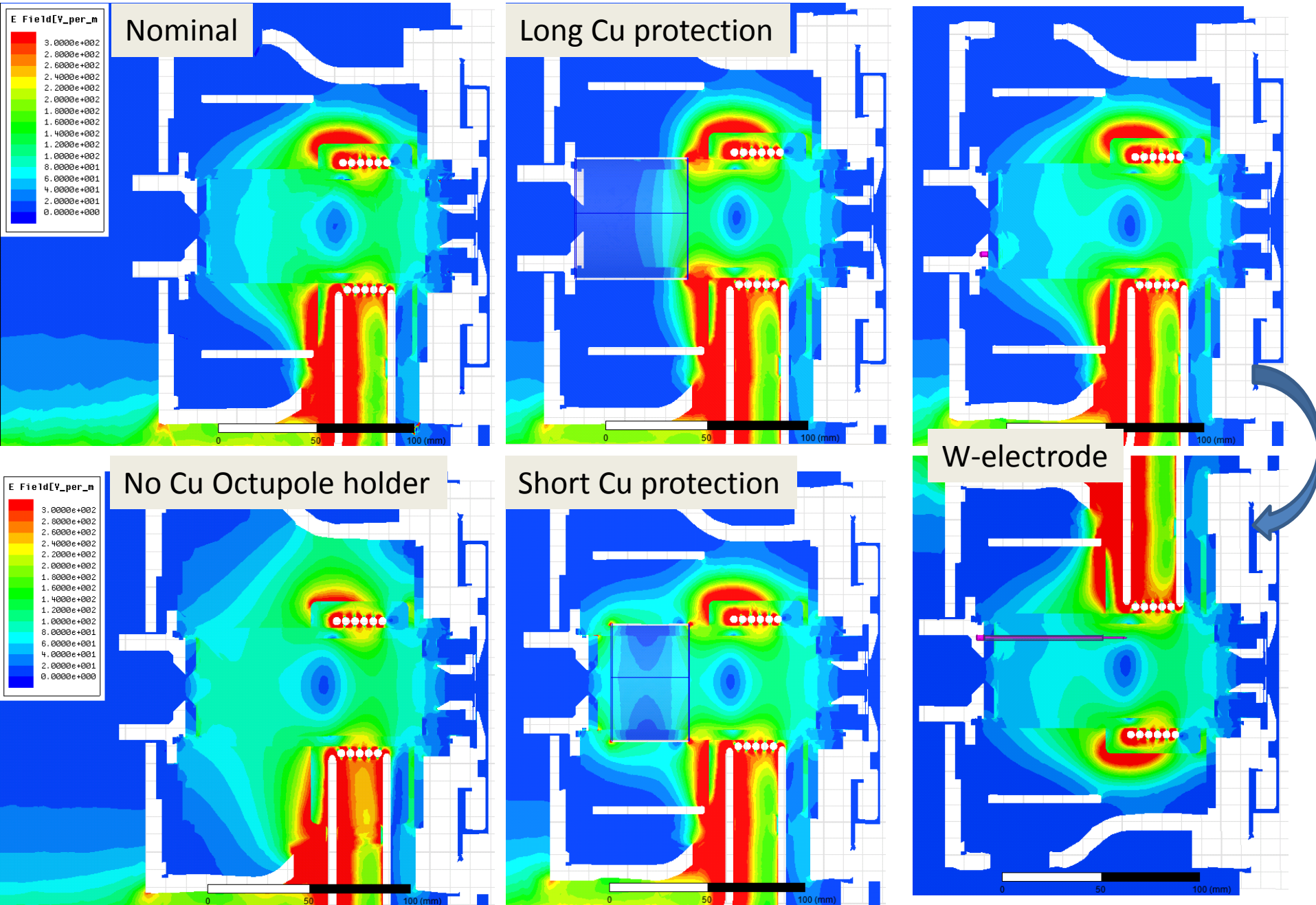
ANTENNA 6 SPIRES - SHORT Cu PROTECTION



- LONG Cu PROTECTION



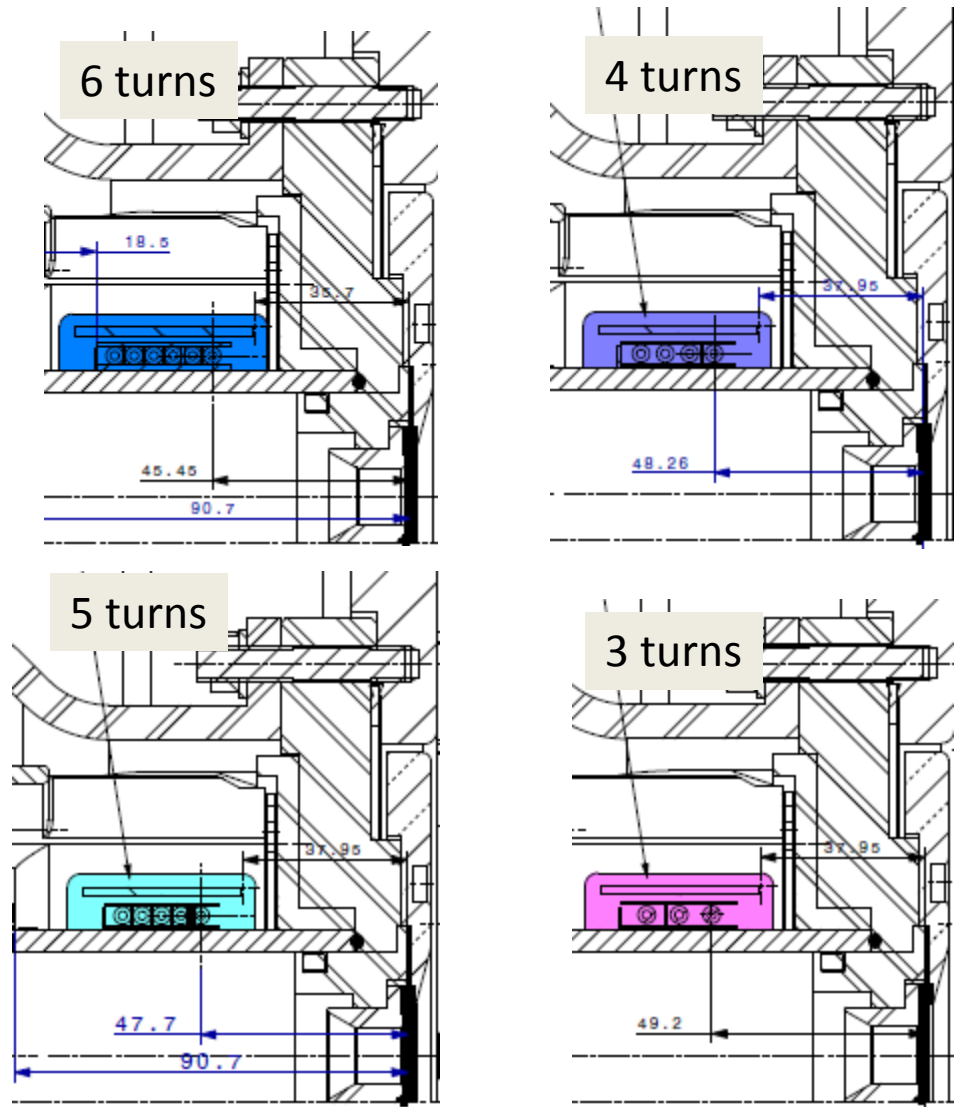
Variations SET 1: E-field distribution



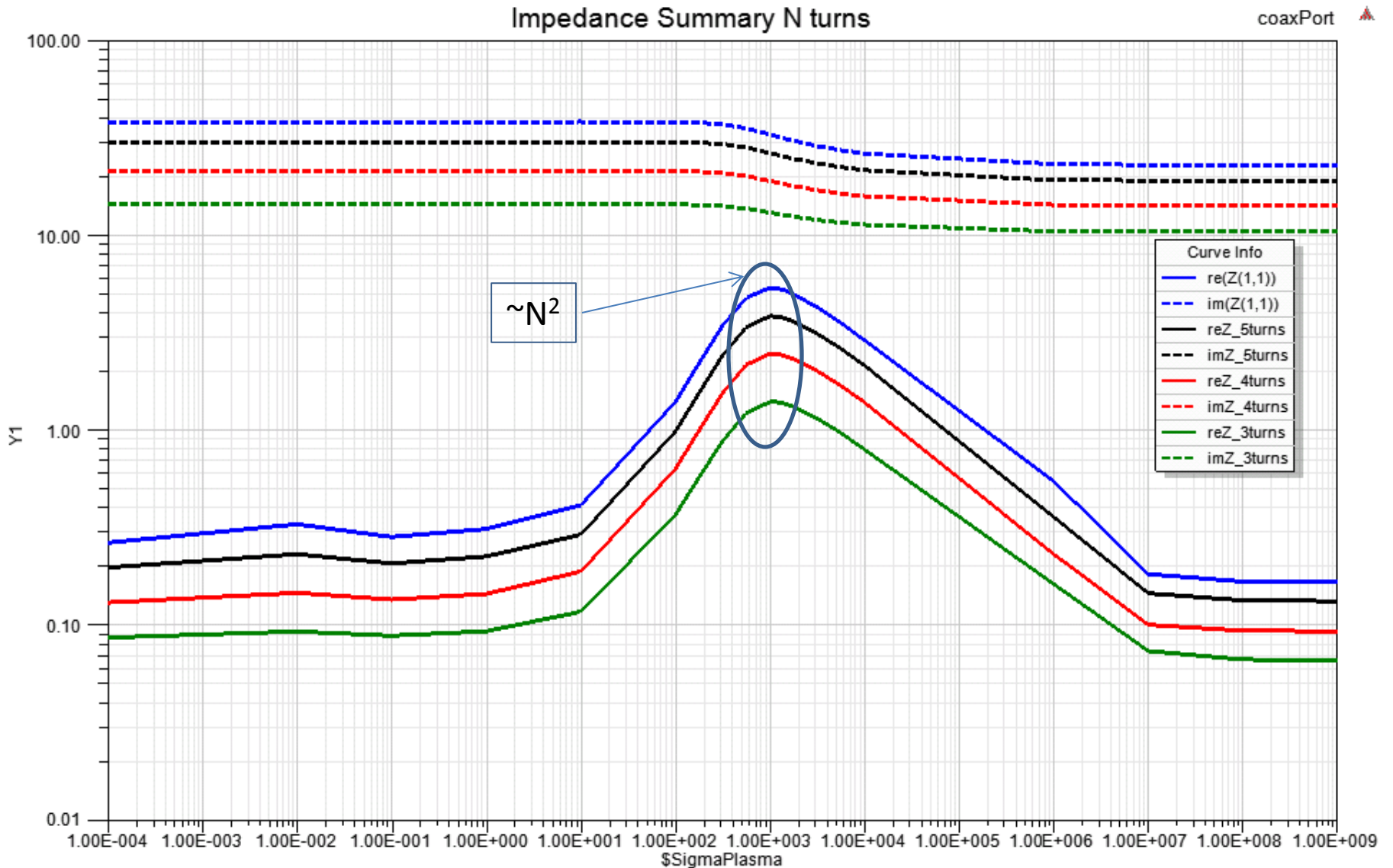
Variation of number of antenna turns

1. Nominal, 6 turns
2. 5 turns
3. 4 turns
4. 3 turns

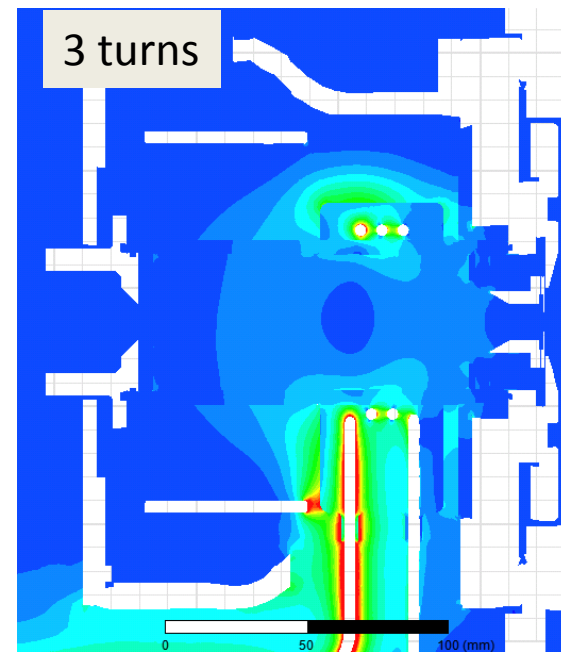
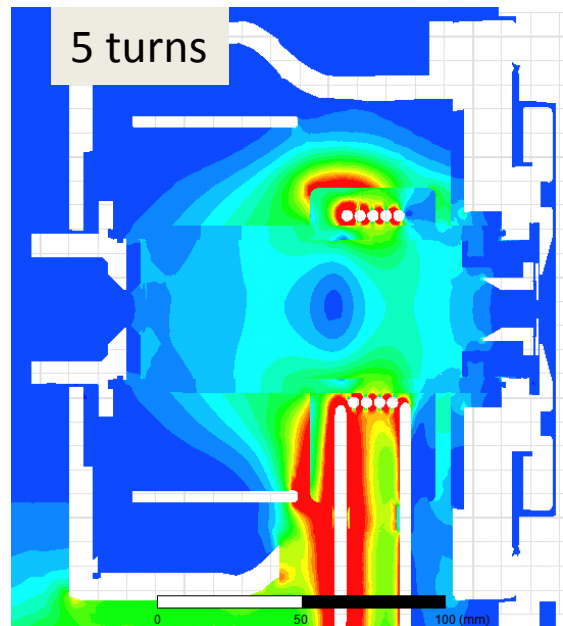
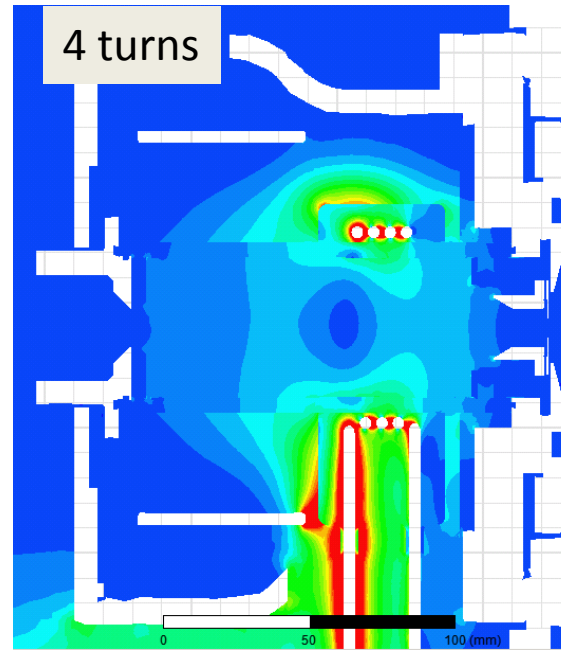
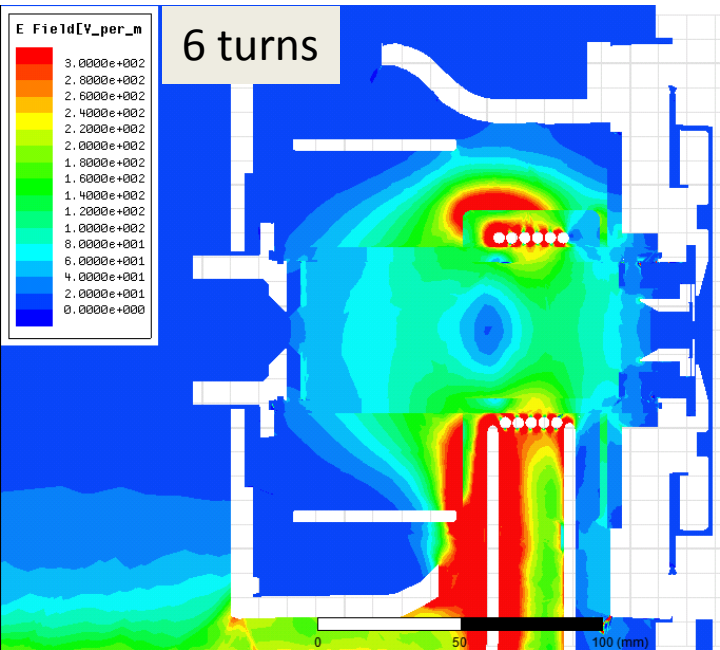
N.B. for 5,4,3 turns the size of epoxy and ferrites are a bit smaller. The same materials are used



Variation of number of turns: impedance



Variation of N turns: E-field distribution



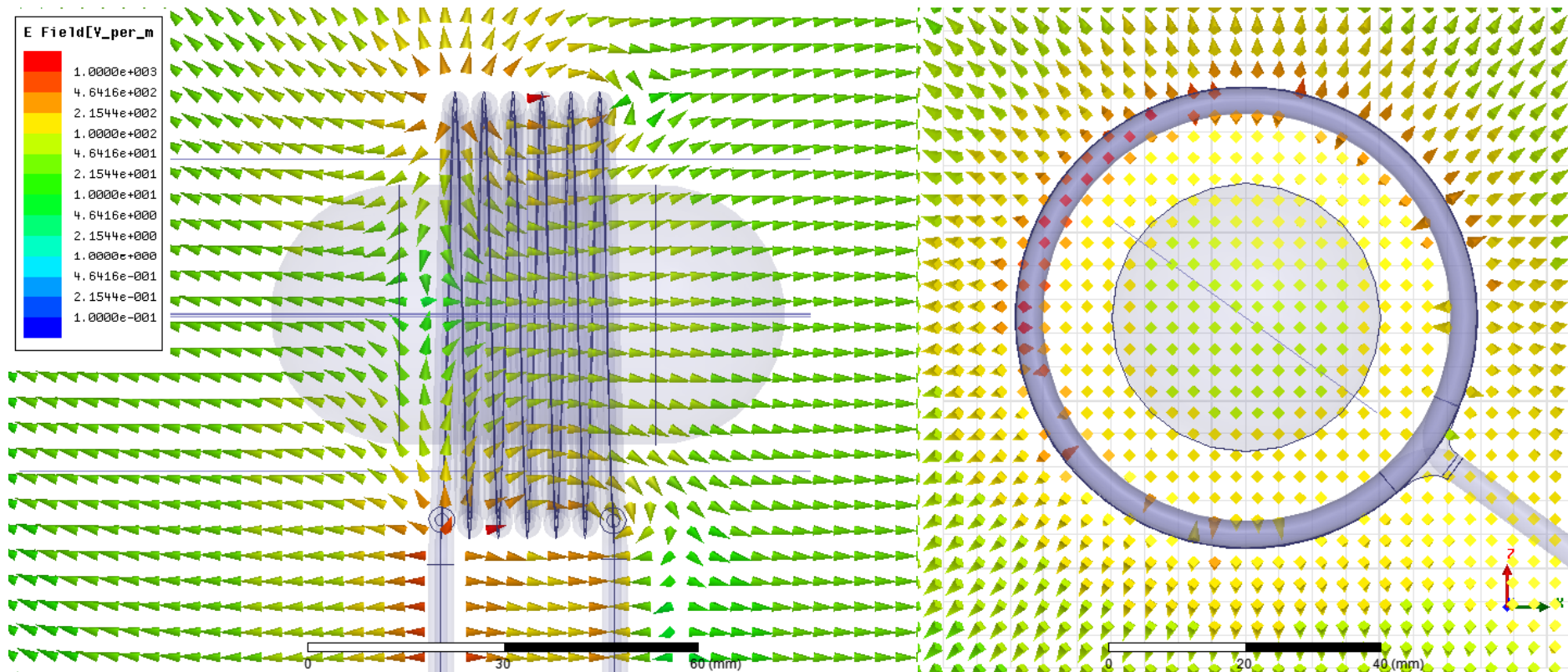
Plasma code

Conclusions

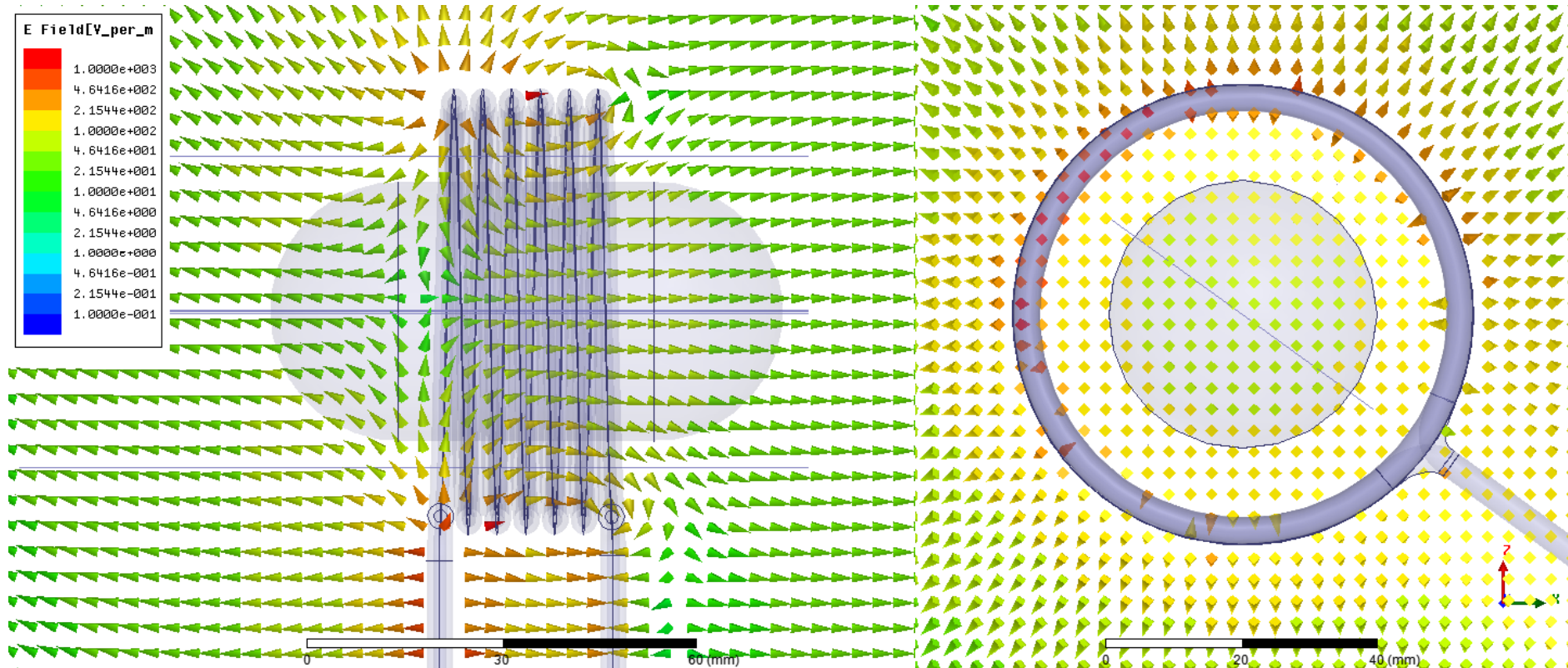
- Full 3D model with realistic material parameters is implemented and simulated using RF code HFSS
- Plasma is modelled as a conductor
- Surface electric field is calculated and compared to discharge limited values
- Without plasma electric field distribution in the plasma chamber is dominated by R,Z components, capacitive electric field
- EM field maps has been calculated for the plasma simulation code
- Impedance of the ion source as a function of “plasma” conductivity is calculated and compared to the RF measurements results
- Matching simulated and measured impedance values gives plasma conductivity which agrees with the one calculated from measured plasma parameters
- Several variations of the IS-01 has been simulated

Spare slides

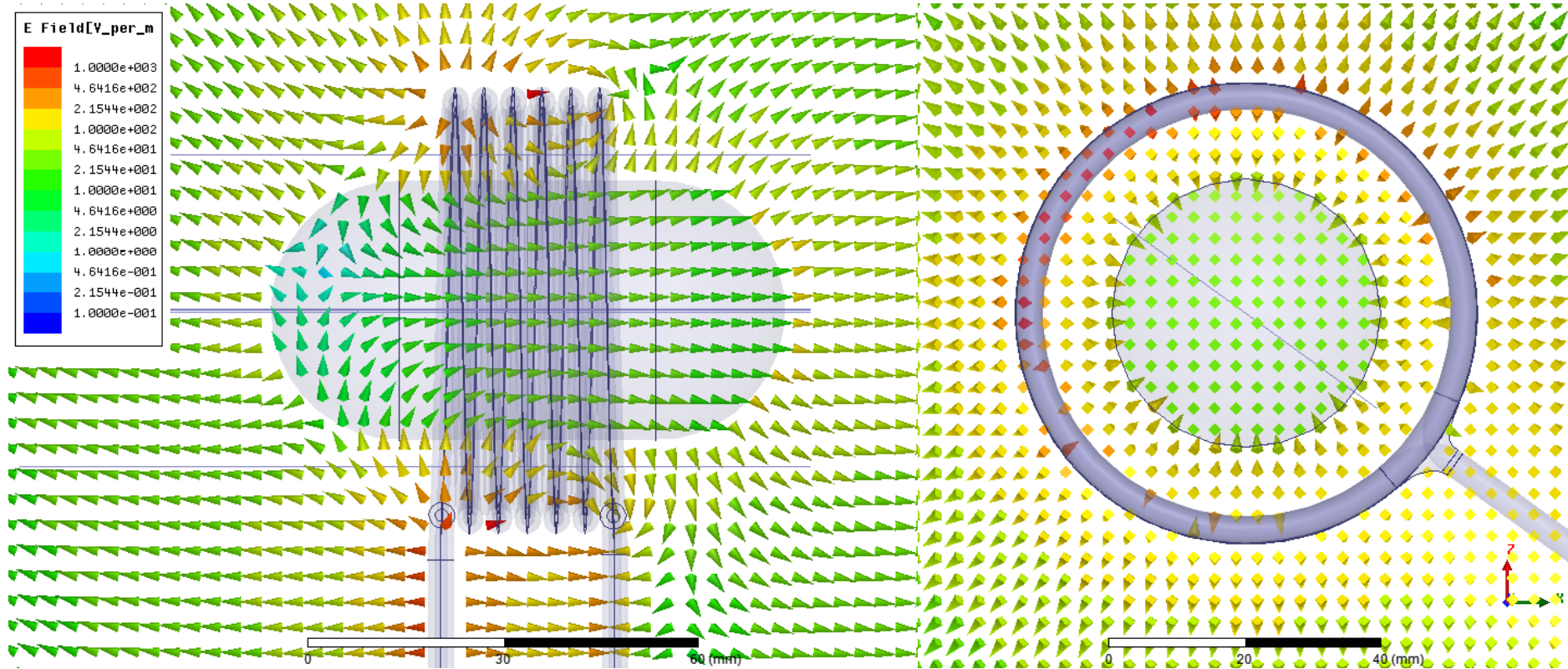
E-field: antenna + “plasma” ($\sigma = 0$ S/m)



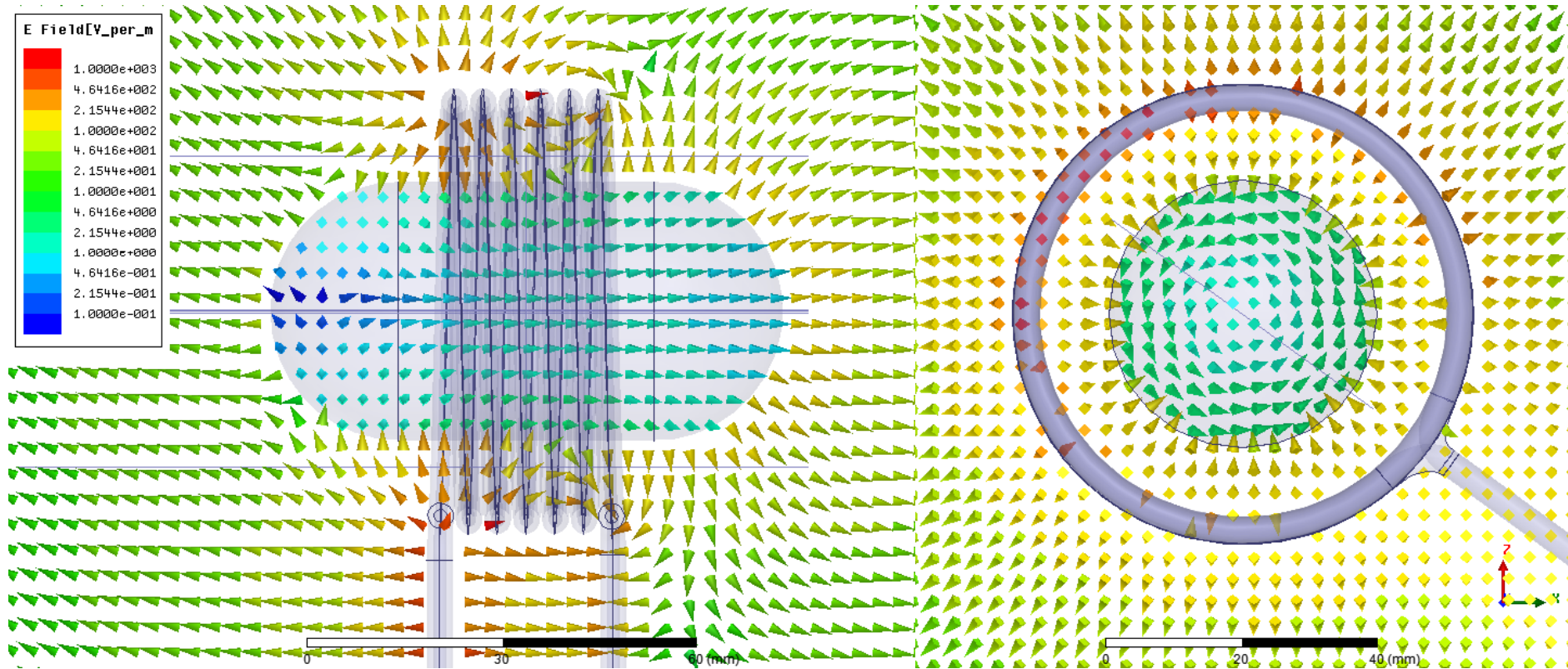
E-field: antenna + “plasma” ($\sigma = 1e-4$ S/m)



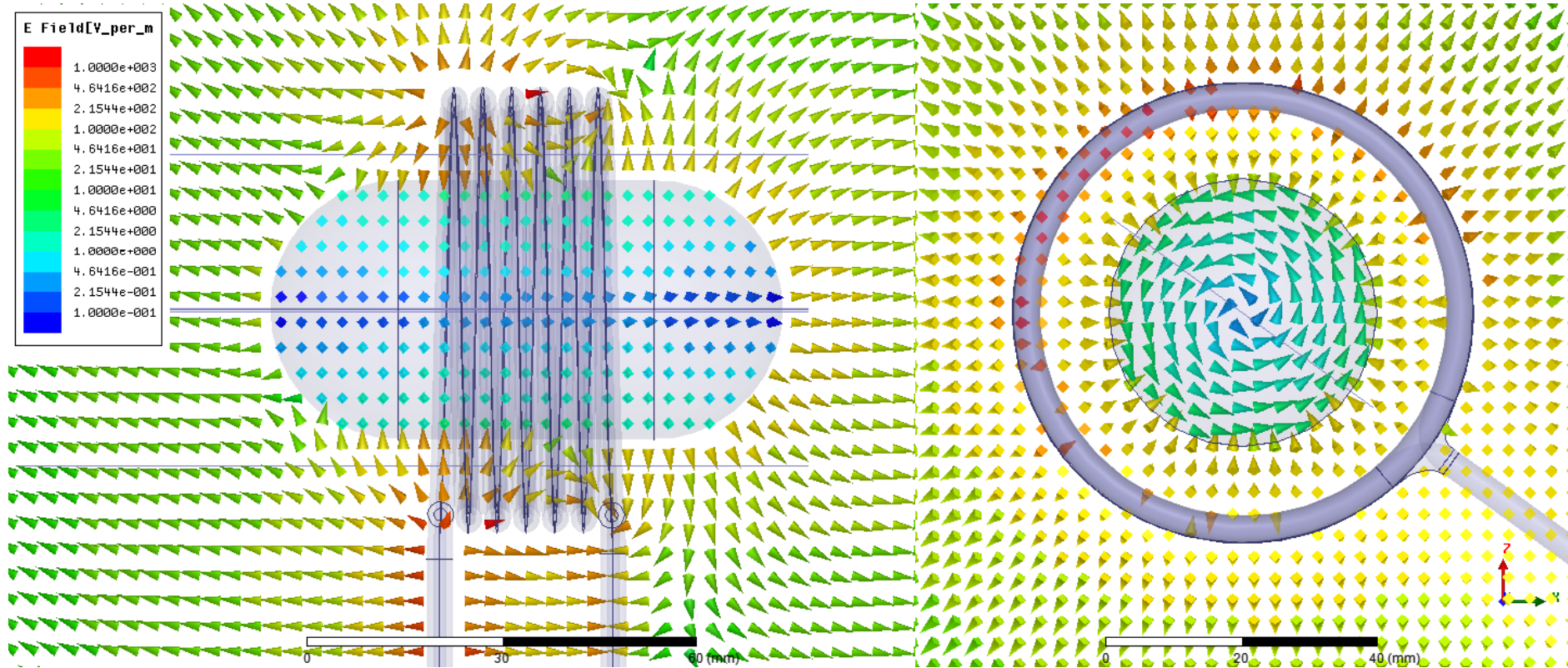
E-field: antenna + “plasma” ($\sigma = 1e-3$ S/m)



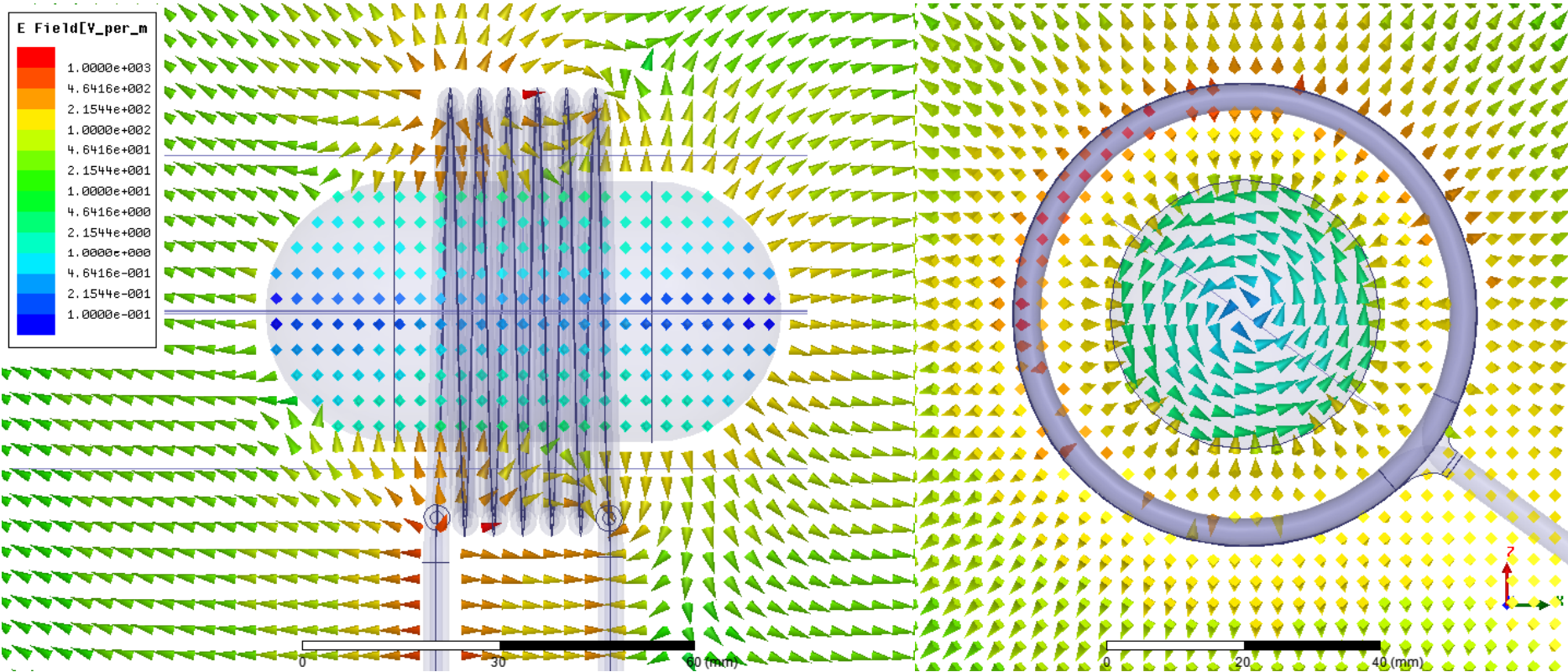
E-field: antenna + “plasma” ($\sigma = 1e-2$ S/m)



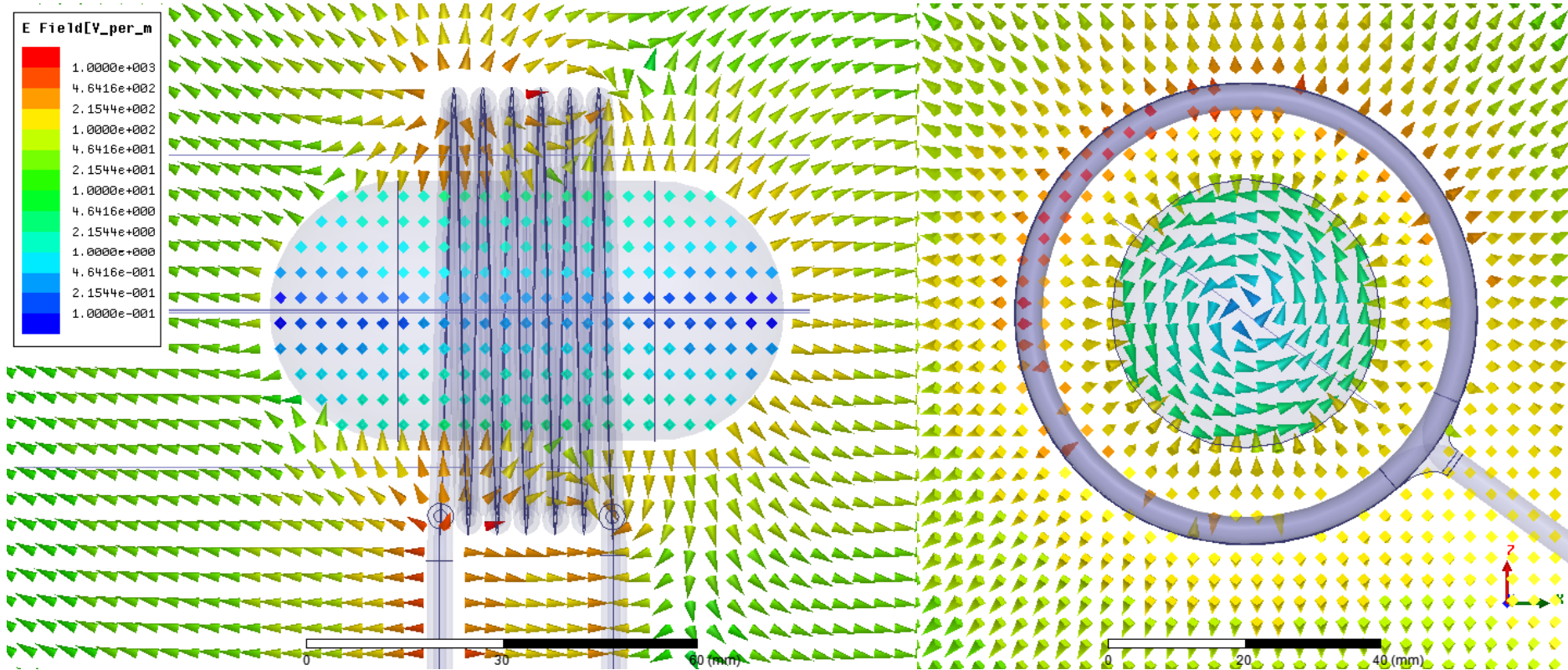
E-field: antenna + “plasma” ($\sigma = 1e-1$ S/m)



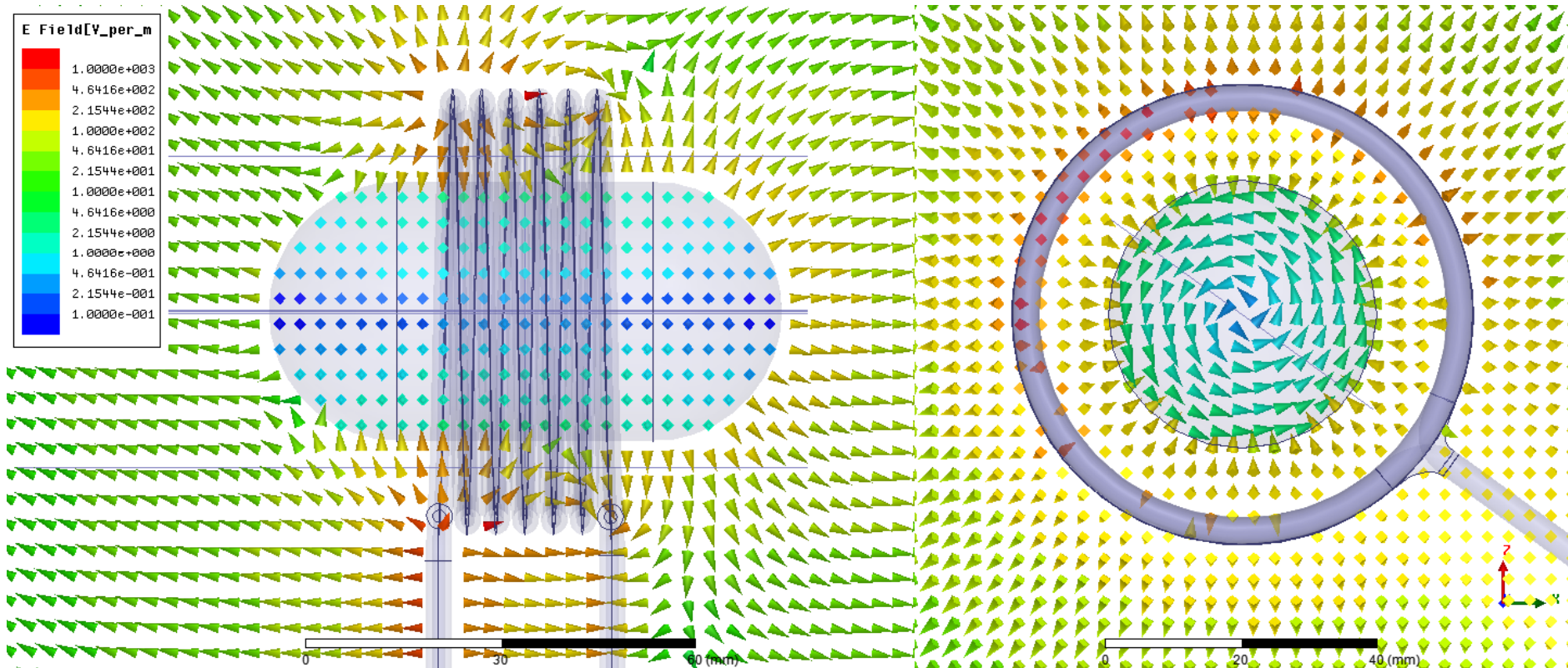
E-field: antenna + “plasma” ($\sigma = 1e-0$ S/m)



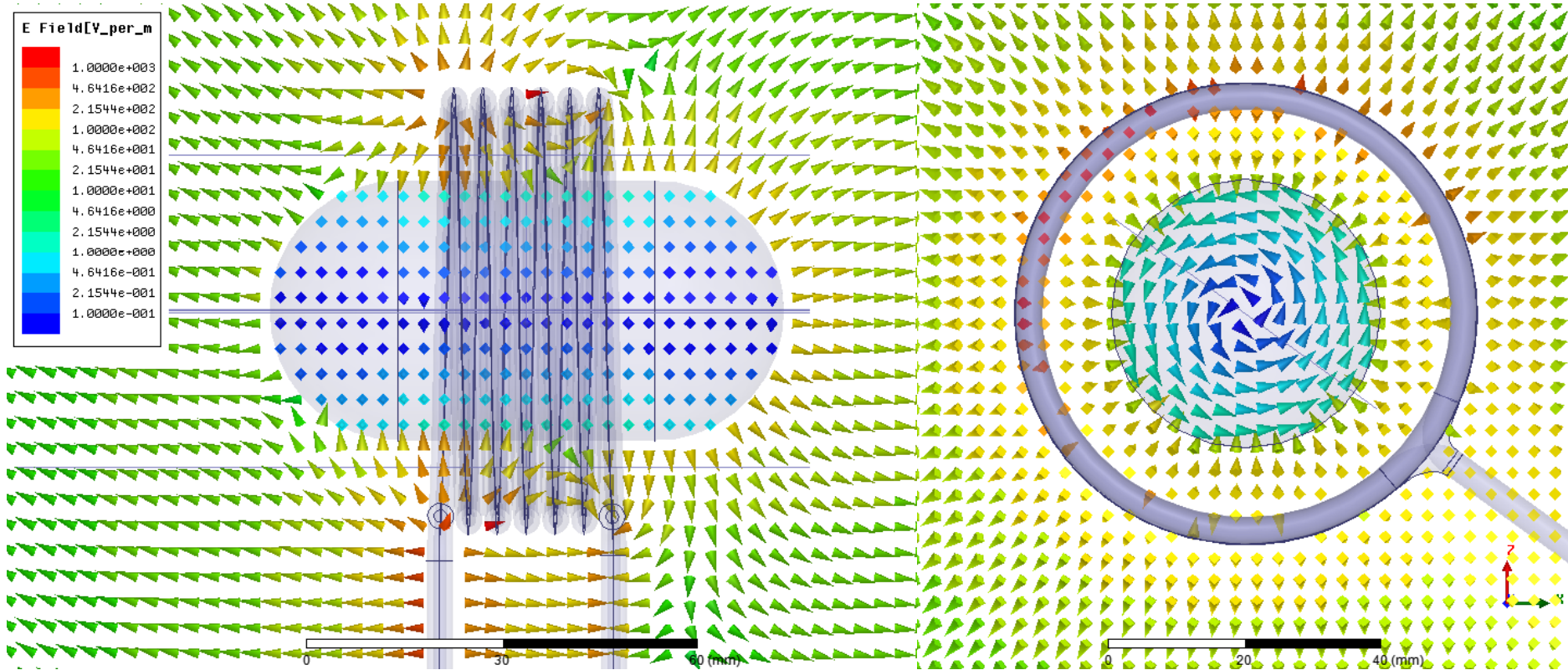
E-field: antenna + “plasma” ($\sigma = 1e+1$ S/m)



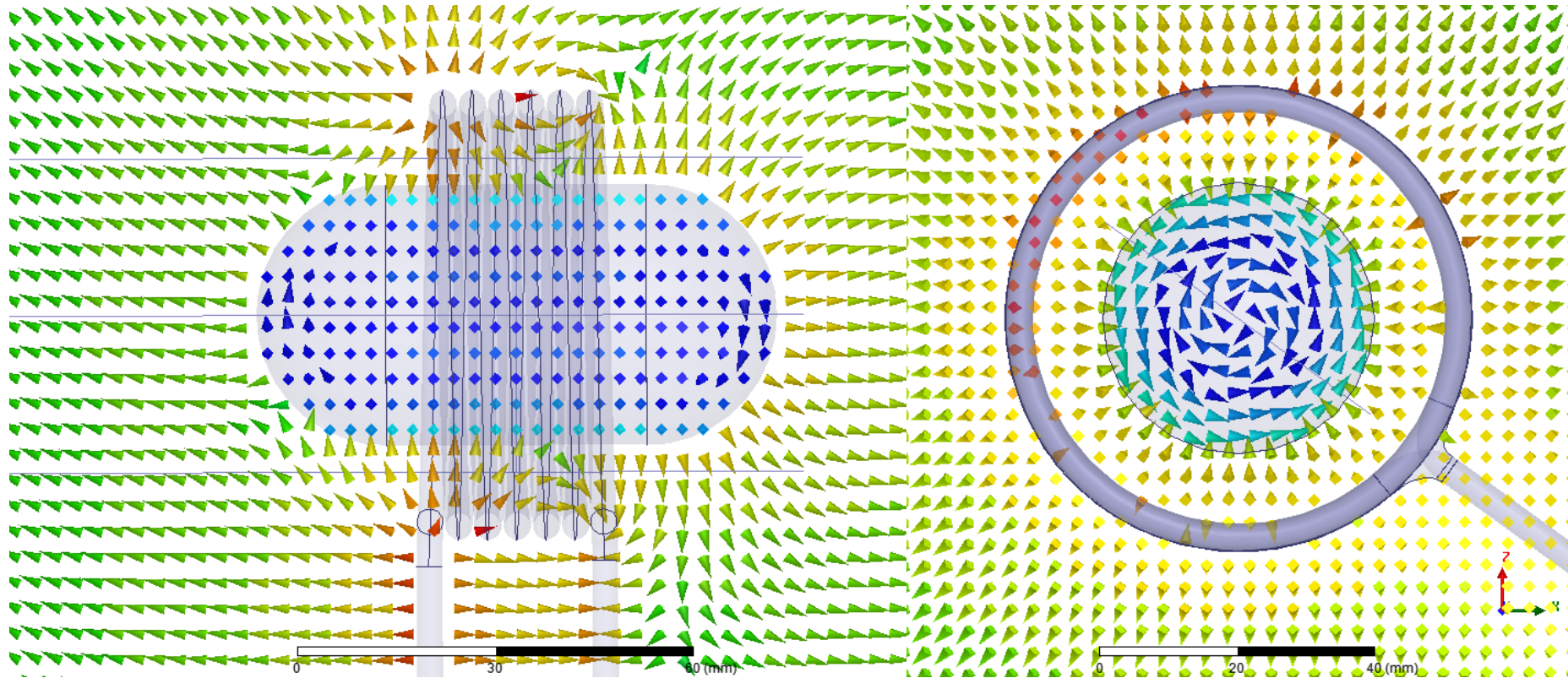
E-field: antenna + “plasma” ($\sigma = 1e+2$ S/m)



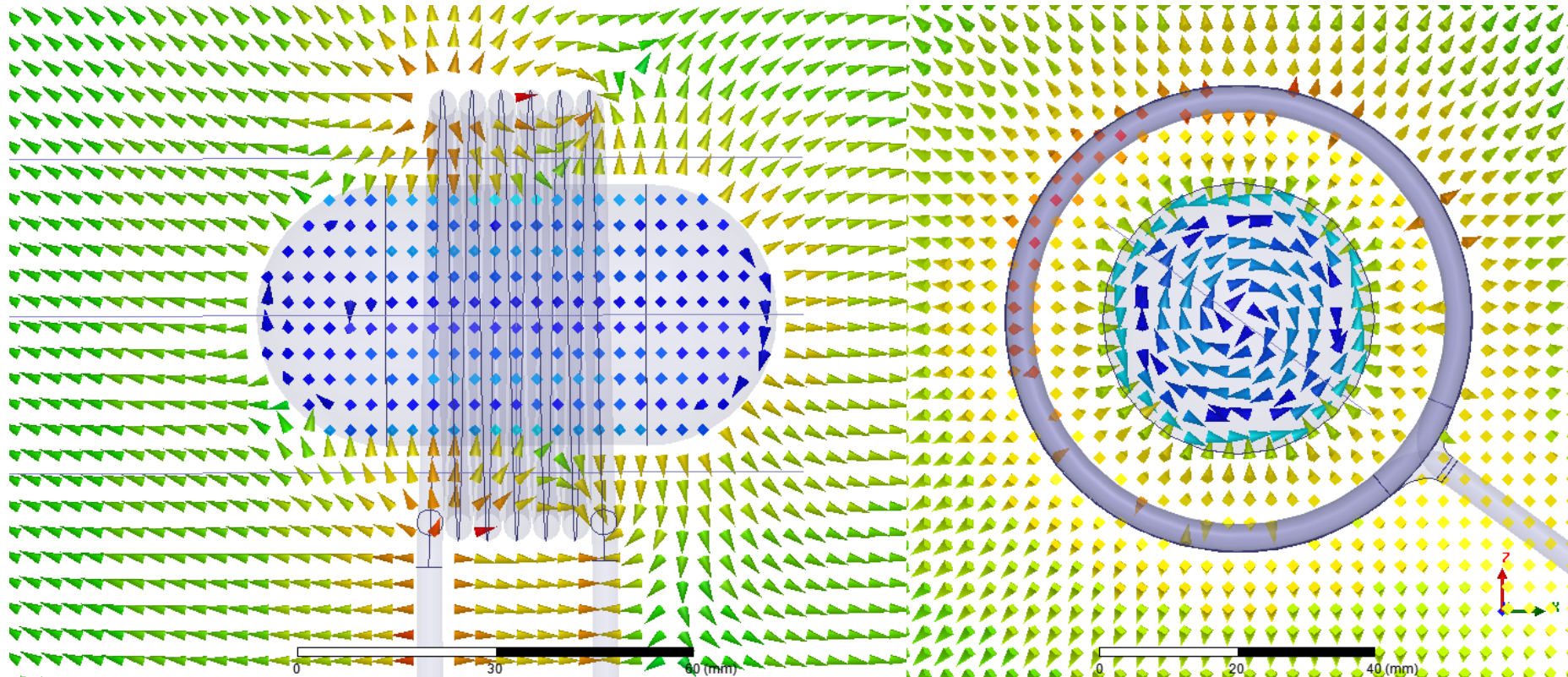
E-field: antenna + “plasma” ($\sigma = 1e+3$ S/m)



E-field: antenna + “plasma” ($\sigma = 2e+3$ S/m)



E-field: antenna + “plasma” ($\sigma = 3e+3$ S/m)



E-field: antenna + “plasma” ($\sigma = 1e+4$ S/m)

